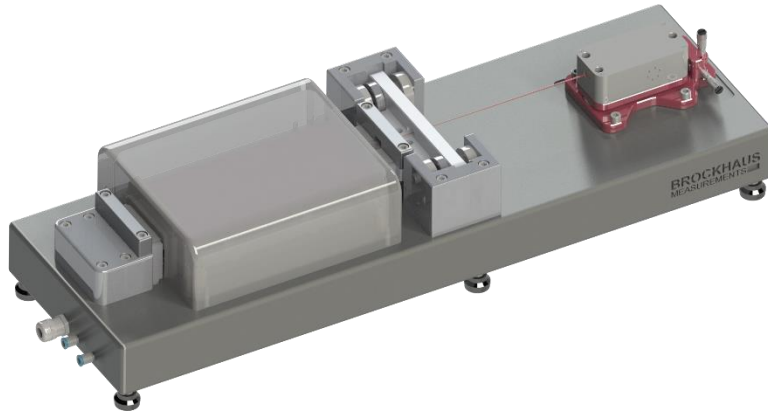


Amorphous Magnetostriction under Tensile Stress System



• System Description:

Magnetostriction measurement sensor for amorphous materials corresponds to the draft of IEC-standard 60404/X "Amorphous SST". Magnetic flux induced in a sample by primary windings, and measured by three secondary coils distributed along the sample, is closed through the bottom yoke. Magnetic field is measured by two H-coils located below and above the sample surface as well as by the current method.

For the compensation of the air-flux a mutual induction, the air-flux coil, is used in a separate housing. The single sheet measuring sensor is protected against electrical overloading.

Measurement can be performed under no stress or tensile stress condition. A Laser interferometer is used for magnetostriction measurements with resolution of 0.3 nm.

• Conditions

- Sinusoidal flux density
Frequency range: 10 Hz - 1 kHz
Peak of flux density up to 2 T
Field strength: 1A/m up to 10,000A/m
- PWM
Switching frequency of 100 kHz
- High Harmonics and Free Curves

• Mechanical Conditions

- Applied Tension
Load: 200 N

• Sample Type:

- Amorphous material
- Sample size 60mm x 300mm
- Sample thickness up to 0.1 mm

• Additional Sensors

- Laser Interferometer (resolution of 0.3 nm)
- Load Cell

